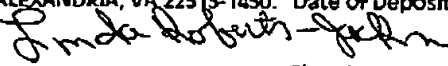


I hereby certify that this paper and fee are being TRANSMITTED VIA FACSIMILE TO: Assistant Commissioner for Patents, P. O. Box 1450, ALEXANDRIA, VA 22313-1450. Date of Deposit: 11/29/04 Name of Person Making Deposit: Linda Roberts-Jackson



Signature

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of _____ :
Markus Schmidt

November 29, 2004
Group Art Unit: 2813

Serial No.:
10/614,545

Confirmation No. 5854
Examiner: Nguyen, Thanh T.

Filed: 07/07/03 :

International Business Machines Corporation
2070 Route 52
Hopewell Junction, NY 12533

TITLE: METHOD FOR THE MANUFACTURE OF MICRO STRUCTURES

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

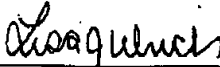
Sir:

Pursuant to the duty of disclosure set forth in 37 C.F.R. 1.56, and further pursuant to the provisions of 37 C.F.R. 1.97 and 1.98, applicants hereby respectfully submit the PTO-1449 and references attached hereto.

In citing these documents, no representation is made nor intended as to the pertinency or non-pertinency of the art, that better art than that listed is not available, or that other art is not applicable.

If any fees are required, however, the Commissioner is hereby authorized to charge such fees to Deposit Account No. 09-0458.

Respectfully submitted,
Markus Schmidt

By 

Lisa J. Ulrich, Registration No. 45,168
Telephone No. 845-894-3338

DE920000065US1

INFORMATION DISCLOSURE CITATION
(Use several sheets if necessary)

Docket Number (Optional)

DE920000065US1

Application Number

10/614,545

Applicant(s)

MARKUS SCHMIDT

Filing Date

7/07/03

Group Art Unit

2813

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
		5,837,426	11/17/1998	TSENG, ET AL.			
		6,042,993	03/28/2000	LEUSCHNER, ET AL.			

FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO
		EP1045291A3	10.01.2001	EUROPE				
		JP02257624 A2	18.10.90	JAPAN				

OTHER DOCUMENTS *(Including Author, Title, Date, Pertinent Pages, Etc.)*

		MicroElectronic Engineering, "SENSITIVITY-ENHANCED DRY DEVELOPMENT PROCESS FOR VUV AND EUV LITHOGRAPHY USING GRAFT-POLYMERIZATION", 1996, PGS 287-290

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with MPEP.

CERTIFICATION OF FACSIMILE TRANSMISSION:

I hereby certify that this correspondence is being facsimile transmitted to the USPTO on the date shown below: 11/29/04

Patent and Trademark Office * U.S. DEPARTMENT OF COMMERCE

SHEET 1 OF 1

Form PTO-A820

(also form PTO-1449)